WS-3000 FULLY-AUTO, HIGH-SPEED SHEET RESISTANCE MEASUREMENT SYSTEM

WS-3000

- Fully automatic, high-speed measurement system for thin film semiconductor process evaluation
- Multi-point, Contact Type using 4-point probe method
- Automatic probe head selection (exchanger) amongst 4 kinds of probe head
- No need to exchange a probe head for each different sample measurement
- Edge 1mm measurement is available by dual measure mode
- FOUP, GEM / SECS compatible
- Sheet Resistance measure range (Ω/sq): 1m to 10M
- Sample Size: Ø 300mm (Optional Ø 200mm)

APPLICABLE MATERIALS

- Semiconductor and Solar-cell materials (Silicon, Polysilicon, SiC etc)
- Conductive thin film (Metal, ITO etc)
- Diffused sample (or layer)
- Silicon-related epitaxial materials
- Ion-implantation sample
- Others: On Request